

WHAT IS CLAIMED IS:

1. A vacuum deposition apparatus comprising:
 - a susceptor for applying heat to a glass substrate for generating plasma;
 - a lift pin for supporting said glass substrate on the susceptor;
 - a robot arm for transferring the glass substrate to and returning the glass substrate from the susceptor;
 - a stopper pin facilitating the stable transfer and return of said robot arm; and
 - a groove formed in a slide part of the susceptor and into which a film-forming material collects upon the deposition process.
2. The vacuum deposition apparatus according to claim 1, wherein the gap between said slide part and said stopper pin is at least 3 mm.
3. The vacuum deposition apparatus according to claim 2, wherein the gap is 10 mm.
4. The vacuum deposition apparatus according to claim 1, wherein the susceptor is made of a quartz material.
5. The vacuum deposition apparatus according to claim 1, wherein the section of said groove formed in the slide part has a polygonal configuration.

6. The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the slide part has a curved configuration.

7. The vacuum deposition apparatus according to claim 1, wherein the bottom face of the groove formed in the slide part includes an incline plane and a perpendicular plane.

8. The vacuum deposition apparatus according to claim 1, wherein the groove formed in the slide part has a V-shaped configuration.